

Navigate, Explore, ... and Discover In Every Research Area

High-Performance Scanning Electron Microscope

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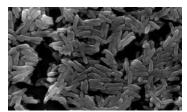


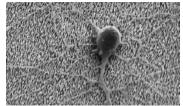


01 Applications

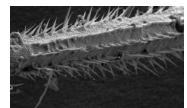


Life Science





Bacteria

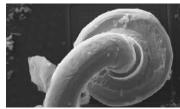


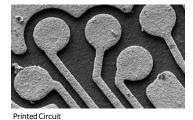
Insect(Fly's head)

Insect(Fly's leg)

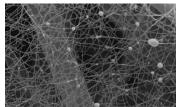


Electronics





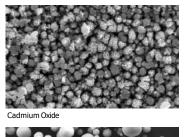
Wire bonding



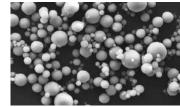
Nano Fiber Semiconductor Package



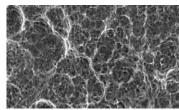
Material Science







abric

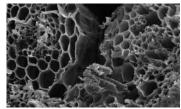


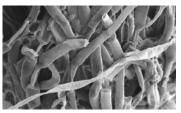
Powde

Dental Implant

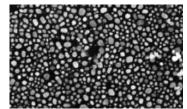


Natural Resource

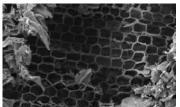




Leaf Cross Section



Stamen



Gold Powder

Cross section of a tree

EmCrafts

High-Performance Scanning Electron Microscope



02 Tabletop SEM Cube-Series

- Most Affordable and Portable
- Full 5-Axis Euccentric Stage
- Integrated EDS System

| Magnification | x20 ~x200,000 |
|--------------------|--|
| Stage | X,Y:40mm/Z:5~20mm/ T:-20~20°/R:360° |
| Maximum SampleSize | 60mm(H), 30mm(V) |





Space Efficiency

Cube-series is most compact Tabletop SEM in the world for its portability and space efficiency. Users can move their SEM by themselves by following the Customer Ser vices directions.



5-Axis Euccentric Stage

Cube-series is the only Tabletop SEM which provides 5-axis euccentric st age(motorized or manual) in the world. Euccentric tilt is essential for 3D r econstruction function.

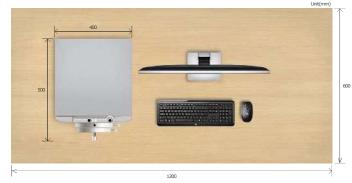


More Affordable Solution

Each laboratory can own its SEM and EDS system on its budget. EmCrafts' Cubeseries is a highly customizable system so that each laboratory can configure its own system. Please contact our sales department for your requirements.



Installation Footprint





CUBE-Series specification

| Model | Cube-1000 | Cube-1100 | Cube-1000A | Cube-1100A | | | | |
|----------------------|--|--|--|---|--|--|--|--|
| Stage | 5-axis Manual X,Y:40mm(-20mm- Z:5~20mm/T:-20 | ~20mm) | 3-axis Motorized XY: 40mm (-20mm ~20mm)/ R: 360° 2-axis Manual Z: 5 ~20mm/T: -20 ~20° | | | | | |
| Variable Pressure | Х | 0 | Х | 0 | | | | |
| Vacuum Mode | High Vacuumonly (<9×10³Pa) | High Vacuum Mode (<9×10³Pa) Low Vacuum Mode (10~230Pa) | HighVacuum only (<9×10³Pa) | High VacuumMode (<9×10³Pa) Low VacuumMode (10~230Pa) | | | | |
| Vacuum System | -Turbo molecular pu -Rotary vanepump | Fully Automated Evacuation System -Turbo molecular pump (Vacuum ready within 3 minutes) -Rotary vanepump -Electrical valvesystem | | | | | | |
| Electron Gun | Precentered Tungste | en Filament | | | | | | |
| Detector | SE (ET-type) | SE (ET-type) BSE (4channel,Semiconductor) | SE (ET-type) | SE (ET-type) BSE (4channel,Semiconductor) | | | | |
| Resolution | 5.0nm (SEImage) | 5.0nm (SE Image) 6.0nm (BSE Image) | 5.0nm (SEImage) | 5.0nm (SE Image) 6.0nm (BSE Image) | | | | |
| Magnification | x20 ~x200,000 | | , | | | | | |
| Acceleration Voltage | 500V ~30kV | | | | | | | |
| Objective IRIS | 20/20/50/100µm (Var | iable aperture) | | | | | | |
| Image Shift | ±50,m | | | | | | | |
| Maximum Sample Size | Horizontal: 60mm, Vertical: 30mm | | | | | | | |
| Advanced Scan Mode | Dynamic Focus, Poin | Dynamic Focus, Point & Line Scan, Tilt Compensation | | | | | | |
| Working Distance | 0~20mm | 0~20mm | | | | | | |
| Automatic Function | Auto Brightness/Contrast, Auto Focus, Auto Gun Alignment, Auto Saturation, Auto Filament / Bias | | | | | | | |
| Image Format | JPG, TIFF, BMP, PNG | | | | | | | |
| Display Mode | Focus Mode : 320x240 pixel, Resizable Preview Mode : 800x600 Slow Mode : Applicable to both preview and focus mode Photo Mode : Up to 3200x2400 | | | | | | | |
| Dimension(mm) | Installation Dimension : 1200(W) x600(D) - Main System : 400(W) x 500(D) x 580(H) - Control Box : 500(W) x 260(D) x 370(H) | | | | | | | |
| Supplied Accessories | Factory-centered Filament Cartridge 1box(10units), Specimen Mounts 1box(10units), Tweezer, Carbon Tape, Hex. Driver 0.89mm (1ea.), Hex. T. Wrench 2.5mm (2ea.) | | | | | | | |
| Operation Device | | ll-in-One 21.5" Workstation keyboard and mouse | | | | | | |
| Optional Devices | | _aBs/CeBs upgrade 3D Imaging in-one Model of SEM-EDS) E-bea | am Lithography | | | | | |
| Power Supply | Single Phase: 100 ~2 | 240VAC, 50/60Hz, 1kVA | | | | | | |

03 Compact SEM Genesis-Series

- 5-Axis Euccentric Stage
- More Value in Less Space
- Straightforward & Intuitive Manual Stage (Genesis-1000 / 1100)
- More Versatile 5-Axis Motorized Stage (Genesis-2020 / 2120)
- Observation of Non-Conductive Sample (Genesis-1100 / 2120)

Genesis series is a high-performance W-filament SEM with x300K magnification and 3nm resolution.

High performance and versatility are integrated in a stylish design which is the most compact of the world in the same category.

EmCrafts-Patented vacuum system enables faster specimen exchange. (within 3min.)

Universal extension ports are available for future upgrade and user customization.

Due to factory-centered filament cartridge, filament exchange is easy and quick.

Images are saved in various formats and can be easily restored for annotation simply by clicking on the thumbnails.



Cost-Effectiveness

- · Genesis series are most affordably priced
- Perfect solution for anylaboratory



Easy Maintenance

- Filament Burn out Notification
- Precentered Filament
- Only 1~2 Minutes are Required for a Filament Replacement
- Remote Diagnostics

Electrical Checkpoints are Probedand Reported





Genesis 1000/1100

- Intuitive 5-axis manual euccentric stage on Genesis-1000/1100 provides easy and straightforward way to move specimens.
- Variable pressure capability of Genesis-1100 enables users to observe non-conductive samples such as biological samples.

| Magnification | x10 ~x300,000 |
|--------------------|--|
| Stage | X,Y:40mm/Z:5~45mm/ T:-20~90°/R:360° |
| Maximum SampleSize | 96mm(H), 50mm(V) |

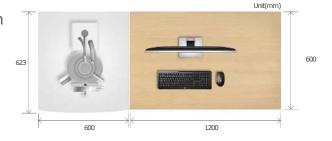
Genesis 2020/2120

- Genesis-2020/2120 provides 5-axis motorized euccentric stage in the same compact design.
- Intuitive "Point & Go" operation enables effortless stage movement in a quick manner.
- Position save and restore function is useful especially for multi-specimen mount.

| Magnification | x10 ~x300,000 |
|--------------------|---|
| Stage | X:90mm, Y:60mm / Z:5~60mm / T:-20~90°/R:360° |
| Maximum SampleSize | 150mm(H), 60mm(V) |



Installation Footprint



GENESIS-Series specification

| Model | Model Genesis-1000 Genesis-1100 | | Genesis-2020 | Genesis-2120 | | | | |
|----------------------|---|--|---|---|--|--|--|--|
| Stage | 5-axis Manual X:40mm (-20mm ~20mm) Y:40mm (-20mm ~20mm) Z:5~45mm T:-20° ~90° R:360° | | X:90mm (-45mm ~45mm) Y:60mm (-30mm ~30mm) Z:5 ~60mm T:-20 ~90° R:360° | | | | | |
| Variable Pressure | Х | 0 | X | 0 | | | | |
| Vacuum Mode | High Vacuum only (<9×10³Pa) | High Vacuum Mode (<9×10³Pa) Low Vacuum Mode (10~230Pa) | High Vacuum only (<9×10³Pa) | High VacuumMode (<9×10³Pa) Low VacuumMode (10~230Pa) | | | | |
| Vacuum System | - Turbo molecular - Rotary vane pump | Fully Automated Evacuation System - Turbo molecular pump(Vacuum ready within 3minutes) - Rotary vane pump - Electrical valve system | | | | | | |
| Electron Gun | Precentered Tungs | ten Filament | | | | | | |
| Detector | SE(ET-type) | SE(ET-type) BSE(4channel, Semiconductor) | SE(ET-type) | SE(ET-type) BSE(4channel, Semiconductor) | | | | |
| Resolution | 3.0nm (SE Image) | 3.0nm (SE Image) 5.0nm (BSE Image) | 3.0nm (SE Image) | 3.0nm (SE Image) 5.0nm (BSE Image) | | | | |
| Magnification | x10 ~x300,000 | | | | | | | |
| Acceleration Voltage | 200V ~30kV | | | | | | | |
| Objective IRIS | 20/20/50/100µm(V | ariable aperture) | | | | | | |
| Image Shift | ±50µm | | | | | | | |
| Maximum Sample Size | Horizontal : 96mm | , Vertical : 50mm | Horizontal : 150mm | n, Vertical : 60mm | | | | |
| Advanced Scan Mode | Dynamic Focus, Po | int & Line Scan, Tilt Compensatio | on | | | | | |
| Working Distance | 0~45mm | | 0~60mm | | | | | |
| Automatic Function | Auto Brightness/Co | ontrast, Auto Focus, Auto Gun Alig | gnment, Auto Satura | tion, Auto Filament / Bias | | | | |
| Image Format | JPG, TIFF, BMP, PN | 3 | | | | | | |
| Display Mode | Focus Mode : 320×240 pixel, Resizable Preview Mode : 800×600 Slow Mode : Applicable to both preview and focus mode Photo Mode : Up to 3200×2400 | | | | | | | |
| Dimension(mm) | Installation Dimension : 1800(W) x600(D) - Main System: 600(W) x623(D) x 1350(H), 130Kg - Rotary Pump : 454(W) x 134(D) x121(H), 22Kg | | | | | | | |
| Supplied Accessories | Factory-centered Filament Cartridge 1box(10units), Specimen Mounts 1box(10units), Tweezer, Carbon Tape, Hex. Driver 0.89mm (1ea.), Hex. T Wrench 2.5mm (2ea.) | | | | | | | |
| Operation Device | Windows10 -based All-in-One 21.5"Workstation -100% controlled by keyboard and mouse | | | | | | | |
| Optional Devices | EBSD(Electron Back Scattered Diffraction) EDS(Energy Dispersive Spectroscopy) WDS(Wavelength Dispersive Spectroscopy) CL(Cathodoluminescent) Imaging Chamber Camera LaBs/CeBs-Upgrade 3D Imaging Raman Spectroscopy | | | | | | | |
| | E-beam Lithograph | | | | | | | |

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04 Big Chamber SEM Veritas-Series

- High Performance and Productivity
- Large Scale Stage Movement

Veritas-series has 5-Axis euccentricmotorized stage to provide easier measurement of large scale samples.

| Magnification | x10 ~x1,000,000 |
|--------------------|---|
| Stage | X,Y:120mm/Z:5~65mm/ T:-20~90°/R:360° |
| Maximum SampleSize | 210mm(H), 65mm(V) |



Application



Large Samples Analysis Veritas-series can analyze large-scale samples conventional SEMs cannot. ex : Wafer, disk



Non-destructive Samples Analysis

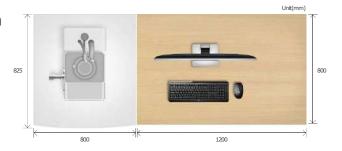
Able to analyze samples without cutting ex: PCB, Semiconductor pattern Analysis



Heavy Samples Analysis

Able to analyze heavy samples up to 2kg ex : Rock, IronOre

Installation Footprint

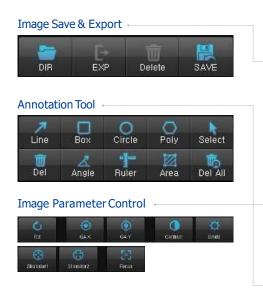


VERITAS-Series specification

| Model | Veritas-LaB6 Veritas-3100 | | | | | |
|----------------------|---|---|--|--|--|--|
| Stage Type | 5-axis Motorized X,Y:120mm(-60mm~60mm) Z:5~65mm T:-20°~90° R:360° | | | | | |
| Variable Pressure | Х | | | | | |
| Vacuum Mode | High Vacuum Mode (<9×10°Pa) High Vacuum Mode (<9×10°Pa) Low Vacuum Mode(10 ~230Pa) | | | | | |
| Vacuum System | Fully Automated Evacuation System - Turbo molecular pump (Vacuum ready within 3 m - Rotary vane pump - Ion pump - Electrical valve system | ninutes) | | | | |
| Electron Gun | Lanthanum hexaboride(LaB ₆) Filament | Precentered Tungsten Filament | | | | |
| Detector | SE Detector BSE Detector (4channel, Semiconductor) | SE Detector BSE Detector (4channel, Semiconductor) | | | | |
| Resolution | 2.0nm (SE Image)/4.0nm (BSE Image) | 3.0nm (SE Image) 5.0nm (BSE Image) | | | | |
| Magnification | x10 ~x300,000 | | | | | |
| Acceleration Voltage | 200V ~30kV | | | | | |
| Objective IRIS | 20/20/50/100µm (Variable aperture) | | | | | |
| Image Shift | ±50µm | | | | | |
| Maximum Sample Size | Horizontal: 210mm, Vertical: 65mm | | | | | |
| Advanced Scan Mode | Dynamic Focus, Point & Line Scan, Tilt Compensation | | | | | |
| Working Distance | 0 ~65mm | | | | | |
| Automatic Function | Auto Brightness/Contrast, Auto Focus, Auto Gun A | lignment, Auto Saturation, Auto Filament/Bias | | | | |
| Image Format | JPG, TIFF, BMP, PNG | | | | | |
| Display Mode | Focus Mode : 320x240 pixel, Resizable Preview Mode : 800x600 Slow Mode : Applicable to both preview and focus r Photo Mode : Up to 3200x2400 | node | | | | |
| Dimension(mm) | Installation Dimension : 2000(W) x800(D) -Main System : 800(W) x825(D) x 1500(H), 200kg -Rotary Pump : 454(W) x 134(D) x 212(H), 22kg | | | | | |
| Supplied Accessories | Factory-centered Filament Cartridge 1box(10units), Specimen Mounts 1box(10units), Tweezer, Carbon Tape, Hex. Driver 0.89mm (1 ea.), Hex. T Wrench 2.5mm (2 ea.) | | | | | |
| Operation Device | Windows 10-based All-in-One 24" Workstation I 10 | 10% controlled by keyboard and mouse | | | | |
| Optional Devices | Chamber Camera 3D Imaging Raman Spectroscopy EDS(Energy Di EBSD(Electron Back Scattered Diffraction) WDS(\ CL(Cathodoluminescence) Imaging E-beam Litho | Wavelength Dispersive Spectroscopy) | | | | |
| Power Supply | Single Phase : 100 ~240VAC, 50/60Hz, 1kVA | | | | | |



05 VirtuosoEasy-to-Use Operation Software









Vacuum Control & Status Monitor



Observation Mode Selection











Automatic Functions Filament/Bias Brigh tness/Contrast Gun Alignment Focus Stigmator



User FriendlyFunctions Multi-User environment Wobble

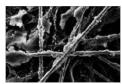
Filament burn-out alarm Customizable annotation

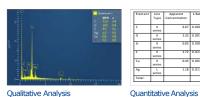


06 Optional Device

1. EDS SYSTEM

- LN2-free operation, Silicon DriftDetector.
- Detects elements from Be(4) to Cf(98).
- Premium Resdution of 129 eV is available.
- Quantitative Analysis, Qualitative Analysis, Multi-Point Analysis, LineScan, Mapping.
- EDS Maker: Oxford, Thermo, Bruker, EDAX, Evex.





| Element | Line Type | Apparent Concentration | k Ratio | Wt% | Wt% Sigma | Standard Label | Factory Standard | Standard Calibration Date |
|---------|--------------|---------------------------|---------|--------|--------------|-------------------|---------------------|---------------------------------|
| c | K series | 6.67 | 0.06666 | 72.81 | 0.42 | CVIt | Yes | |
| 0 | K series | 2.32 | 0.00782 | 19.76 | 0.42 | SiO2 | Yes | |
| Si | K series | 0.05 | 0.00037 | 0.07 | 0.01 | SiO2 | Yes | |
| s | K series | 2.72 | 0.02340 | 4.42 | 0.06 | Fe52 | Yes | |
| Cu | K series | 0.45 | 0.00451 | 0.78 | 0.05 | Cu | Yes | |
| Ag | L series | 1.18 | 0.01185 | 2.16 | 0.06 | Ag | Yes | |
| Total: | | | | 100.00 | | | | |

Point and Area Analysis

Line Scan







Mapping

2. ION SPUTTER COATER



- Operating principle: Top Electrode discharge system
- Ionization power: ~50mA(Max: 500V)
- Target: 50mm(Ø) x 0.1mm thick, Disc type(Au, Pt)
- Instrumentcase: 270(W) x470(D) x 385(H)
- Power requirements: 220V/ Single phase AC 50/60Hz, 10A
- Weight: 22kg
- Rotary Pump: 16L/min[at60Hz]

3. BSE Defector

- Semiconductor Type, 4 Channel Detector.
- BSE detector make it possible that sample with non-coating is observable and the boundary interface of alloy sample can bedisentangled.







BSE Detector

SE Image

BSE Image

4. Holder









Multi Holder for 7 pin Stubs

Big Mount

45°Pin Stub Holder

Set Screw Vise

5. Filament





LaB₆ Filament

Factory-Centered Filament Cartridge

High-Performance Scanning Electron Microscope



6. Critical Point Dryer

- Critical point dryer is an instrumental device which is used to pre process biological specimens such as plants, insect, livertissue, ne rve cell, brain tissue etc.
- At critical point, the specimen is dried using CO₂. The original shape of specimen would be maintained and analyzed without causing s urface tension by moisture and necrosis of biological tissue by de hydration.



7. Freeze Dryer

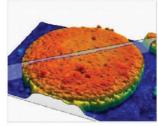
- Freeze dryer is to fix, dehydrate biological specimen with minimal shrinking and deformation.
- Electronic temperature control ranging from 0°Cto 40°C. Rapid adjustment of temperature,10 minutes for adjustment from 40°Cto 5°C.

8. Cool Stage

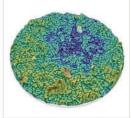
Cool stage offers a flexible heating/cooling to observe biological specimen. Biological specimen can be observed using cool stage with minimal dehydrationand deformation at lower temperature. Easily damaging Specimen by E-beam is also observable using cool stage.

9. 3D Reconstruction S/W

Many nano-scale require depth information bet most optical microscope and scanning electron microscope
haven't delivered successful solutions so far. EmCrafts Products wupplies state-of-the-art 3D restruction s
oftware which is capable of 3D imaging from multiple images at different angles or illuminations which can
replace expensive solutions such as atomic force microscope.







10. More advanced applications are available

- EBSD(Electron Back Scattered Diffraction)
- WDS(Wavelength Dispersive Spectroscopy)
- CL(Cathodoluminescence) Imaging
- Chamber Camera
- Raman Spectroscopy
- Etc.

High-Performance Scanning Electron Microscope

Cube Series / Genesis Series / Veritas Series

Navigate, Explore, ... and Discover In Every Research Area







Distributor in Greece:



T. 210 72.43.529 - 6979 64.23.95 **email:** info@apples.com.gr **site:** www.apples.com.gr



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